

Figure 1
(Prior Art)

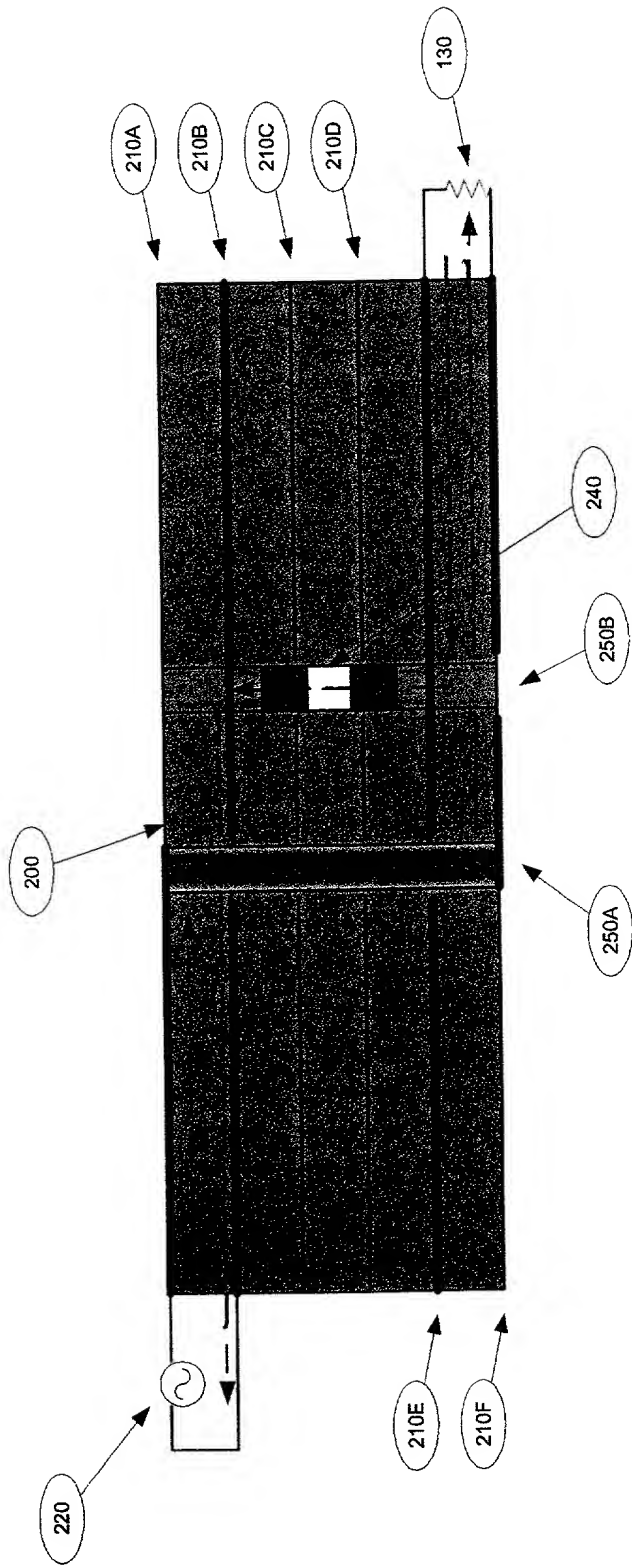


Figure 2

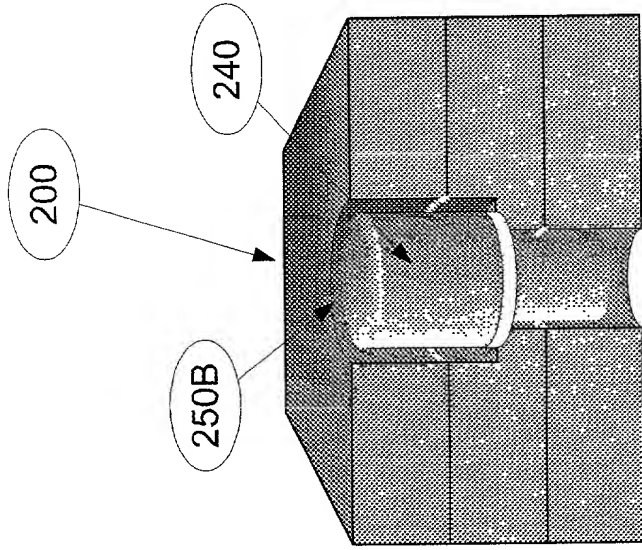


Figure 3A

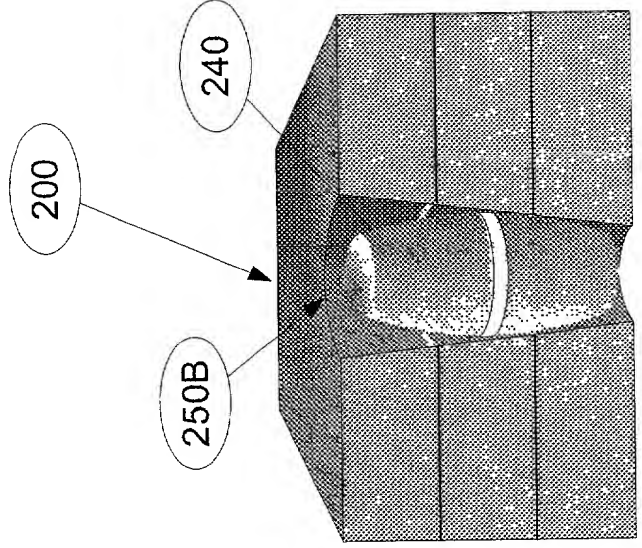


Figure 3B

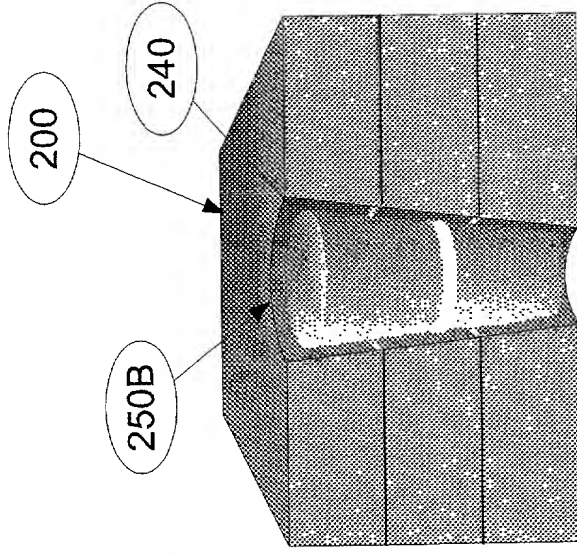


Figure 3C

FIG. 4 is a schematic diagram of a system 400 for processing a substrate 410. The system 400 includes a substrate 410, a processing chamber 420, a processing chamber 430, a processing chamber 440, and a processing chamber 450. The substrate 410 is positioned in the processing chamber 420. The processing chamber 420 includes a substrate 410, a processing chamber 420, a processing chamber 430, a processing chamber 440, and a processing chamber 450. The processing chamber 420 includes a substrate 410, a processing chamber 420, a processing chamber 430, a processing chamber 440, and a processing chamber 450.

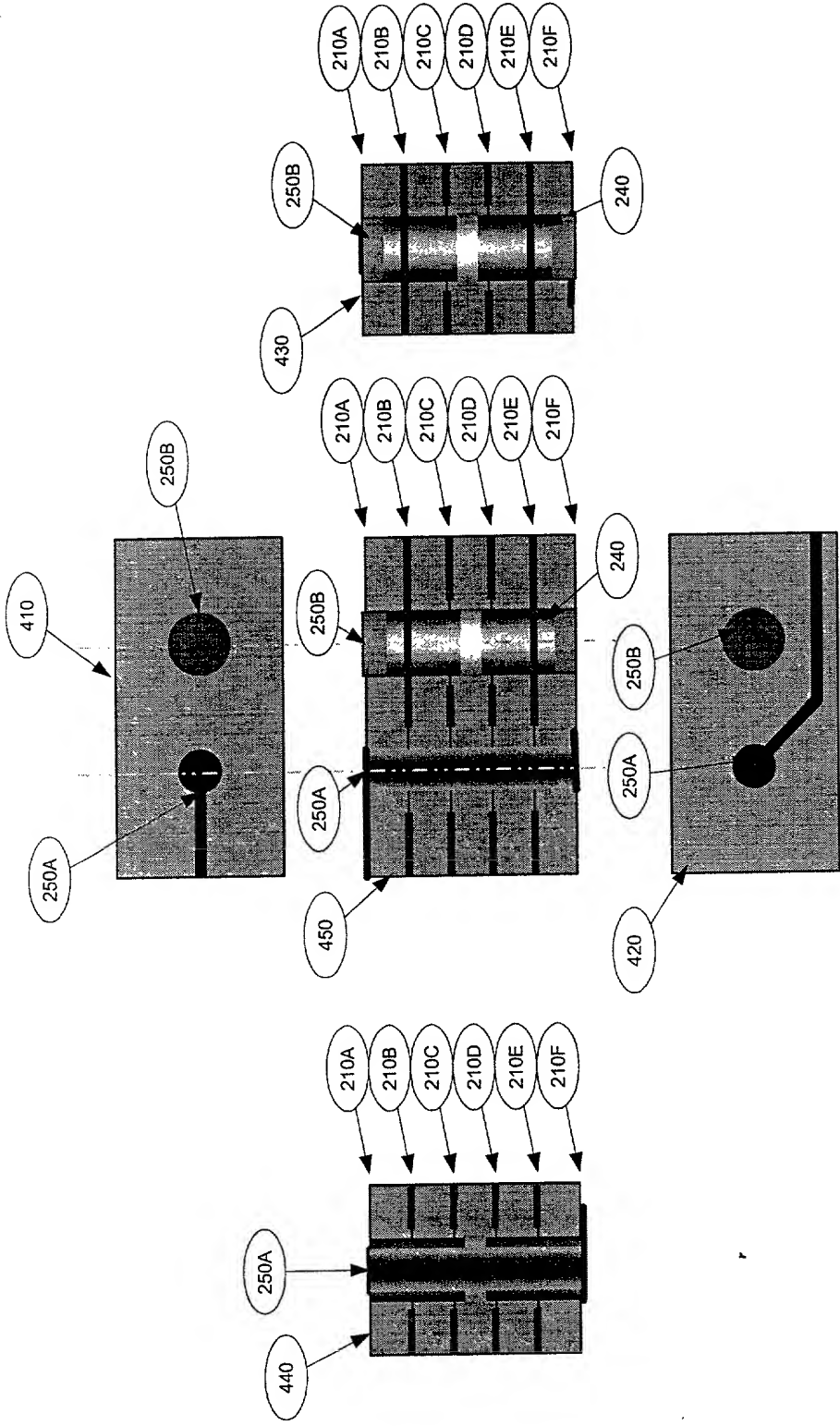
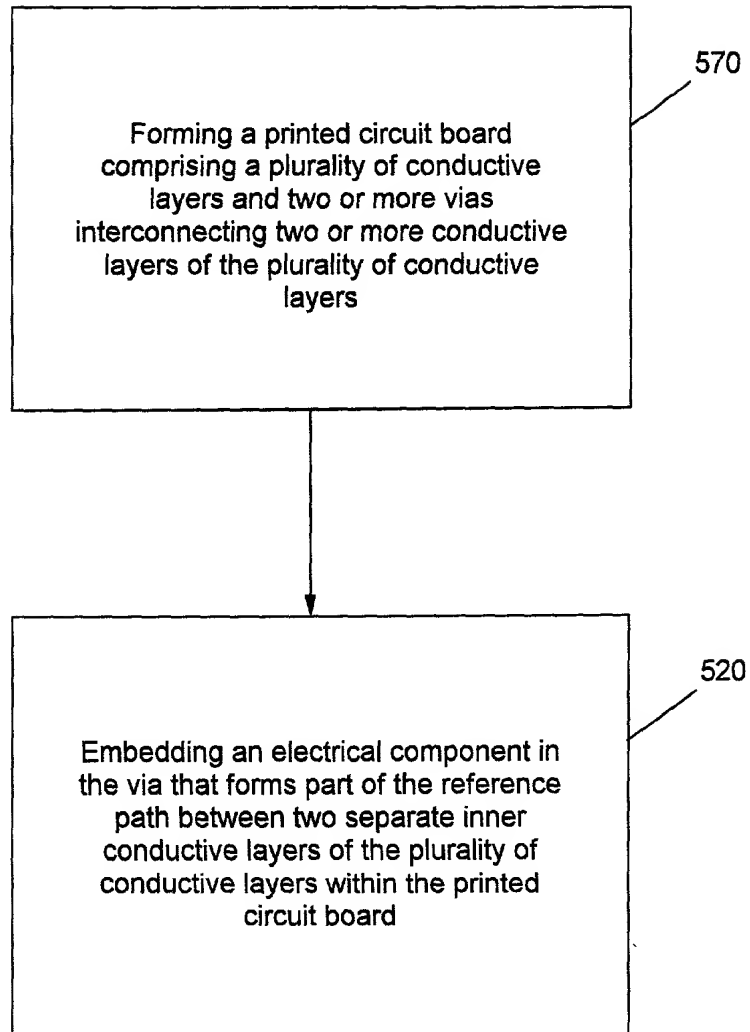


Figure 4

500

Figure 5



600



Figure 6

